

# Preliminary Programme

## SEM Course

20–22 March 2017

Problem Solving with Scanning Electron Microscopy  
and X-ray Microanalysis

### 1st Day: Scanning Electron Microscopy

#### Morning:

Basic (E)SEM (lecture): electron guns - lenses electron - specimen interaction, signals  
SEM-imaging (lecture): secondary and backscattered electrons - detectors contrast formation (topographic and material)

#### Afternoon:

Image recording (lab): working distance, focus, astigmatism contamination, damage

### 2nd Day: X-ray Spectrometry

#### Morning:

Specimen preparation (lecture):

Basic X-ray spectrometry (lecture): information depth, inelastic scattering, applications

X-ray Analysis (lecture): detectors (wavelength - energy dispersive), artefacts qualitative - quantitative analysis - mapping

#### Afternoon:

X-ray acquisition (lab): beam energy, count rate, acquisition time spectra - mapping acquisition

### 3rd Day: Applications

#### Morning:

Analysis of specimens from the participants (lab)

#### Afternoon:

Additional methods by scanning electron microscopy (lecture): EBSD, Variable pressure SEM, Dual beam (SEM-FIB)

Alternative Analytical methods (lecture): Transmission electron microscopy Vibrational spectroscopy

**Organizer:** Stefan Mitsche

**Lectors:** Stefan Mitsche, Peter Pölt

**Operator:** Hartmuth Schröttner

**Special arrangements:** Separate Courses for groups (at least 4 persons) on request